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Photoresponse of wafer-scale palladium diselenide films prepared by selenization method

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Abstract

Palladium diselenide (PdSe₂) films exhibit a high charge carrier mobility and sensitivity in photodetection. In this work, wafer-scale PdSe₂ thin films with controllable thickness have been synthesized by the selenization of Pd films. A PdSe₂-based photodetector can detect a broad wavelength ranging from 420 nm to 1200 nm. The responsivity and detectivity can reach 1.96×10^3 A W⁻¹ and 1.72×10^{10} W / Hz^{1/2} at $V_{SD} = 3$ V, respectively. The figure of merit of the photodetection are comparable to the mechanically exfoliated PdSe₂ based photodetector. This work demonstrated that selenization is a facile method to synthesize PdSe₂ films in large scale and the films are promising for broadband photodetection.

Keywords: palladium diselenide, two-dimensional layered material, photodetection, field effect transistors

Introduction

After graphene was discovered in 2004, the research of two-dimensional layered materials (2DLMs) have been raised. Some 2DLMs exhibit layer-dependent bandgap² and hence their spectral absorption can be tuned by controlling their thickness. For instance, MoS₂ has a band gap transition from indirect band gap value of about 1.2 eV to direct band gap of 1.8 eV by reducing the thickness from bulk to monolayer, 3-8 while black phosphorus (BP) has a band gap transition from 0.3 eV to 2 eV.9 Also, under the field effect transistors architecture, the MoS2 and BP flakes showed layerdependent charge carrier mobility and photoresponse under light illumination. 10 Similar layer-dependent properties are also found in other 2D semiconductors and semimetals such as WS₂, MoSe₂ and PtSe₂. 11-13 Combining the high electrical performance and the vast choices of materials for optical absorption, which make 2DLM family suitable for photodetector applications. ^{2,14,15}

The application of the 2DLM-based field effect transistors (FETs) is suffering from non-scalable production. Until now, most of the FETs were based on the exfoliation of bulk crystals. In most of these works, the dimensions of the flakes are usually within the range of several hundred microns. 16-22 For the next generation photodetectors, a better controllability on thickness, area and shape are required. 14 In this aspect, sulfurization and selenization of metal precursor films show a trade-off between material quality and large-area with controllable thickness. This fabrication method has already showed its advantages in noble metal based 2DLMs such as PtSe₂ and PdSe₂. 12,23-25

Among the transition metal dichalcogenide family, PdSe₂ has a unique in-plane pentagonal crystal structure. ³⁰ As a high mobility semiconductor/semimetal, the PdSe₂-based photodiode demonstrated excellent performance. ^{24,28} The research on large-area PdSe₂ films is still scarce. In this work, the PdSe₂ films were fabricated by selenization of Pd films. The films exhibited homogeneous semi-transparency across a 2" sapphire substrate. A broad photodetection ranging from 420 nm to 1200 nm was demonstrated. A high responsivity of 1.96 × 10³ AW⁻¹ for 980 nm was also achieved.

Experimental Section

Chemicals and substrates:

Selenium powder (99.99%) was purchased from Sigma Aldrich. Polished 2" in diameter c-plane (0001) sapphire wafer and polished 4" SiO₂/Si (500 nm thick) were purchased from Silicon Valley Microelectronics, Inc.

*PdSe*² *film fabrication method:*

Palladium (Pd) films on sapphire substrates were prepared by a DC magnetron sputtering system. The 99.95 % purity Pd target was used. After the pressure of the chamber reached 1×10^{-6} Torr, argon gas was introduced, and the pressure was kept at 5×10^{-3} Torr. The deposition power was 10 W during the Pd deposition. The deposition time was adjusted to control the Pd thickness and hence the thickness of the PdSe₂ samples.

During the selenization process, the substrates were placed inside the heat zone of a tube furnace and the selenium powders were placed upstream and 15 cm apart from the substrates. The argon gas flow rate was 90 sccm and the pressure was kept at 5 Torr. The temperature of the substrates and Se powder were kept at 350 °C and 300 °C, respectively.

*Fabrication of PdSe*² *transistor:*

A thin layer of polystyrene (PS) was deposited on the PdSe₂ by spin-coating. To ensure the cleanliness and the intrinsic performance of the PdSe₂, the PS/PdSe₂ composite was peeled off by allowing deionized water to penetrate into the interface between PdSe₂ and sapphire slowly. The as-synthesized PdSe₂ thin films were then wet-transferred on a SiO₂/Si with pre-defined Cr/Au electrode. The film was further annealed at 120

°C for 30 minutes for better contact. Finally, toluene was used to remove the PS under ambient conditions and the PdSe₂ transistors were ready to use.

Electrical measurement of PdSe₂ transistor:

All the electrical measurements were carried out with a Keithley 4200-SCS at room temperature in a nitrogen filled glove box with O_2 and $H_2O < 10$ ppm. For photodetection, the light emitting diodes with emission wavelengths of 420 nm, 530 nm, 895 nm, 980 nm and 1200 nm were used to illuminate the transistor channel.

Materials characterization:

High resolution transmission electron microscopy (HRTEM), selected area electron diffraction (SAED) and energy-dispersive X-ray spectroscopy (EDX) measurements were performed by JEOL JEM-2100F Field Emission Electron Microscope. Carbon coated copper grids were used as sample holders. X-ray diffraction (XRD) measurement was conducted by the Rigaku SmartLab X-ray Diffractometer. Raman spectroscopy of PdSe₂ was measured by LabRAM HR 800 Raman Spectrometer. Thickness measurements were determined by atomic force microscope (AFM, Asylum MFP-3D Infinity). The UV-vis-NIR absorption spectroscopy was obtained by Perkin Elmer LAMBDA 1050 UV/Vis Spectrophotometer.

Results and discussion

Figure 1a shows the photograph of a sapphire substrate, sputtered Pd film and the selenized PdSe₂ film. The Pd and PdSe₂ films are semi-transparent and PdSe is darker. The temperature profile of selenization in tube furnace and the calibration curve of the PdSe₂ thickness against the sputtering time are shown in Figure S1a and S1b (Supporting Information), respectively. Figure S2 provides the AFM images of the film thickness. The thicknesses are about 1.7 nm, 4.9 nm, 9.2 nm, 10.4 nm with the Pd deposition time of 15 s, 30 s, 60 s, 75 s, respectively. Figure 1b shows the Raman scattering spectra under the 433 nm laser excitation. The Raman modes of A_g^1 ($\approx 143 \text{ cm}^{-1}$), A_g^2 ($\approx 206 \text{ cm}^{-1}$), B_{1g} ($\approx 222 \text{ cm}^{-1}$) and A_g^3 ($\approx 256 \text{ cm}^{-1}$) are well consistent with the literature. 26,29 The peak intensity was also varied with the thickness of the PdSe2. Figure 1c shows the intensity ratio of A_g^1/A_g^3 , it decreases as the thickness increases.

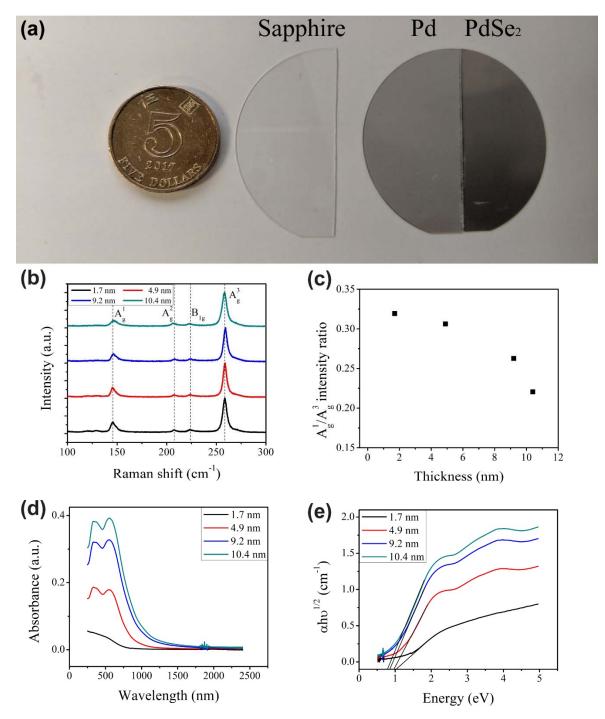


Figure 1(a) The photographs of sapphire substrate, Pd and PdSe₂ on sapphire. (b) The Raman scattering of the films with various thickness. (c) the ratio of A_g^{1}/A_g^{3} with various thickness. (d) The UV – vis – NIR absorption spectra and (e) the tauc plot of the PdSe₂ films.

The ratio could serve as an indicator of $PtSe_2$ film thickness. Similar result was also found in the literature.²³ The UV - vis - NIR absorption spectra of the $PdSe_2$ films on sapphire are shown in **Figure 1d**. The absorbance and absorption range can be enhanced by

increasing the thickness. Besides, there exists two obvious absorption peaks at 330 nm and 558 nm in the films which thickness reaches 4.9 nm or above. **Figure 1e** shows the Tauc plot of the samples. The optical band gap of the films decreases as the film thickness increases. The bandgap of the PdSe₂ films is thickness dependent.

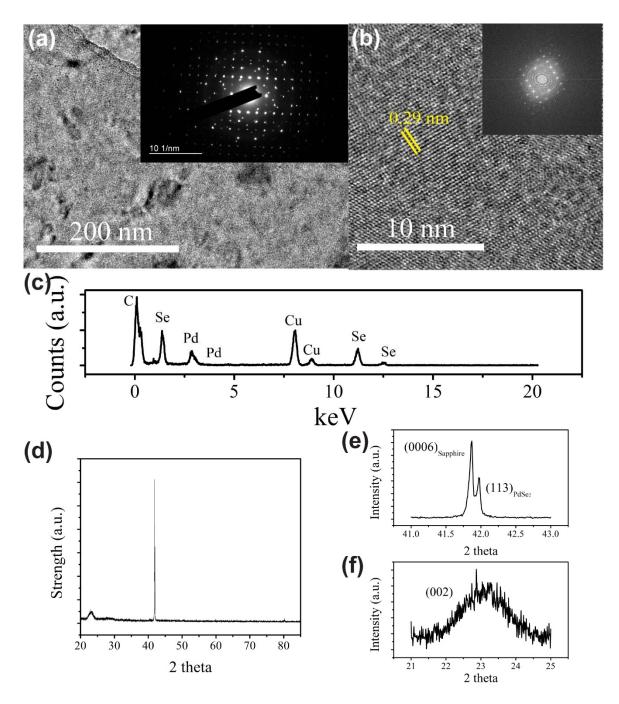


Figure 2 Material characterization of the 9.2 nm-thick PdSe₂ film. (a) The TEM image and SAED pattern (inset) of the film. (b) The HRTEM image and FFT (inset) of the film. (c) EDX spectrum of the film measured on the carbon coated copper grid. (d) XRD of the films. Enlarged XRD spectrum of (e) 41° to 43° and (f) 21° to 25°.

The 9.2-nm-thick PdSe₂ film was selected to conduct TEM and XRD measurements. **Figure 2a** shows the TEM image of the film with the SAED pattern is shown in the inset. SAED patterns were randomly selected on the copper grid to investigate the crystallinity of the films in a microscopic view. The regular spot sequences with superimposition of the rings patterns are shown. The superimposition implies the film is polycrystalline. The

crystal quality is comparable to the previous sulfurization/selenization works.^{25,30} The HRTEM image of the film is shown in **Figure 2b.** The lattice constant of 0.29 nm is consistent with the (200) planes of the previous reported PdSe₂ film.³¹ Moreover, the EDX spectrum of the film was acquired during the TEM measurement. It shows the signals of carbon, copper,

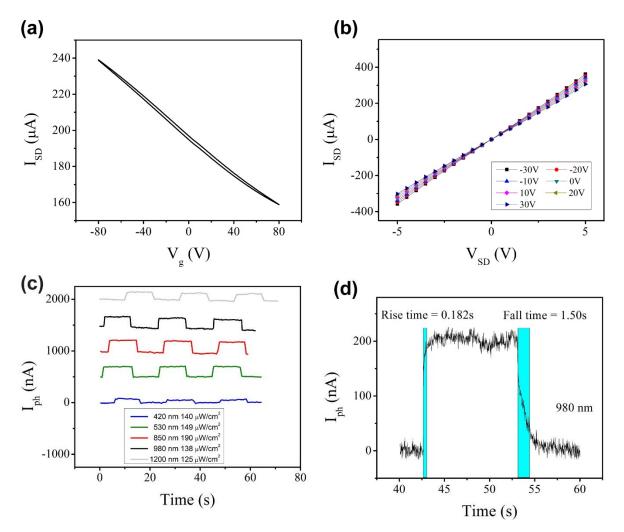


Figure 3 The electrical and light detection performance of the 9.2 nm – thick PdSe₂ transistors. (a) Dual sweep transfer characteristics curve and (b) output characteristics curve, (c) the photocurrent of the transistor under different light wavelength. The offsets of 500 nA, 1000 nA, 1500 nA and 2000 nA are added to separate the data of photoresponses. (d) the response time of device under 980 nm (Intensity: $138 \mu \text{W} / \text{cm}^2$).

The stoichiometric ratio of the film was investigated by filtering the signals of carbon and copper. The remaining atomic ratio of Pd:Se is close to 1:2. No other elements can be found in the spectrum. Furthermore, the film on sapphire was measured by XRD. **Figure 2d-2f** show the broad range and magnified XRD spectrum. The (002) (\approx 22°) and (113) (\approx 41.9°) peaks matches the XRD peaks of single crystal PdSe₂. The average crystal domain size of the (113) plane is about 148 nm according to the Scherrer formula D = (0.94 λ) / (β cos θ), where D = average crystallite size, β = FWHM in radians, θ = Bragg angle, λ = 0.154 nm.

Meanwhile, bottom gate FET configuration was further employed to investigate the transport properties of the 9.2 nm – thick PdSe₂ film. **Figure 3a** and **3b** shows the dual sweep transfer and output characteristics curves of the

PdSe₂ FET. The transfer characteristic curve shows the p-type characteristic with an on/off ratio of 1.50 under the sweep of gate voltage. Since the measurements were conducted in a nitrogen filled glove box with O_2 and H_2O concentration < 0.1 ppm, trappings from surface adsorbate were eliminated. The small hysteresis of the transistor indicates that the intrinsic traps of the polycrystalline PdSe₂ do not hinder the movement of the charge carriers effectively. The output characteristic curves show a typical resistance change of semiconductor channel in FET structure under different gate voltages. The field effect mobility μ =1.20 cm² V⁻¹ s⁻¹ was calculated according to the equation: 32,33

$$\mu = \frac{L}{WC_{OX}V_{ds}} \times \frac{dI_{DS}}{dV_g}$$
 (1)

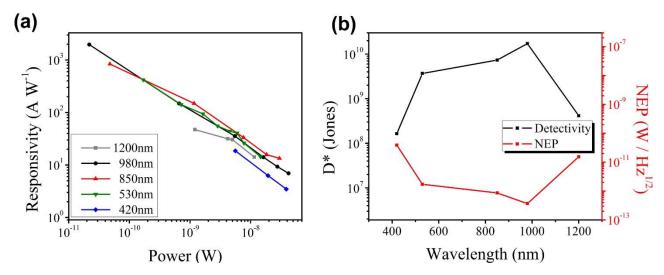


Figure 4 (a) The responsivity of the 9.2 nm – thick PdSe₂ transistors. (b) The specific detectivities (D*) and noise equivalent powers (NEP) of the 9.2 nm – thick transistors.

where channel length L and width W is 5 µm and 800 µm respectively, the capacitance C_{ox} ($C_{ox} = \epsilon_0 \epsilon_r / d$, $\epsilon_0 = 8.854 \times 10^{-12} \, F m^{-1}$, ϵ_r for SiO_2 is 3.9, and SiO_2 thickness d = 300 nm) and $V_{SD} = 3V$.²

The FET was then tested for photodetection under $V_{\text{SD}} = 3V$ and $V_g = 0V$. The light emitting diodes (LEDs) with wavelengths of 420 nm, 530 nm, 850 nm, 980 nm and 1200 nm were served as the light sources. During light illumination, the PdSe2 channel absorbs photon energy and generates electron-hole-pairs (EHPs). The voltage bias V_{SD} will separate the electron and holes to different electrodes and the photocurrent will be detected. The device shows a broadband photoresponse from 420 nm to 1200 nm. The photocurrents (the difference of the currents with and without light illumination) are shown in **Figure 3c.** They show the stable photocurrent change under the same light intensity illumination. A rise time of 182 ms and decay time of 1.50 s was recorded (Figure 3d). The log-log plots of the photocurrent and power are shown in the Figure S4. Under different sensing wavelengths, the log-log plots show the linear relationship between I_{ph} and P. Hence the typical $I_{ph} \propto$ P^{β} relationship can be experimentally established. The β values in the plots are ranging from 0.13 to 0.49 and less than the ideal value 1. The results indicate that there are loss of photocurrent in the transistor.³⁴ However, it is reasonable that the polycrystalline PdSe₂ has material defects, the defect sites would act as the recombination location of photogenerated carrier.^{35–37}

As the figure of merit in photodetection, responsivity R, and specific detectivity D* were calculated. The responsivity R

of the FET under the illumination of the aforementioned lights was then calculated by:

$$R = \frac{I_{ph}}{P} = P^{\beta - 1} \tag{2}$$

where P is the illuminated power and I_{ph} is the photocurrent. I_{ph} is deduced by the subtraction of the currents with and without light illumination. Among all the testing conditions, the highest responsivity is found to be 1.96×10^3 A W⁻¹ when 980 nm light with a power of 22 pW is used. The lowest responsivity is recorded (3.47 A W⁻¹) when 420 nm light is used. **Figure 4a** shows the photoresponsibility of the device at various wavelengths. The responsivities show the linear relationship in the log-log plot of responsivity and power, which are also in agreement with Equation (2). The gain of the transistor is about 2.48×10^3 , which is estimated by the equation:³⁸

$$G = \frac{I_{ph}}{P} \times \frac{E}{q_{p}} \tag{3}$$

where E is the photon energy of the incident light, η is the external quantum efficiency (assuming 100%) and q is the elementary charge.

The specific detectivity D* is another figure of merit of the photodetectors. To evaluate the D* values of the FET under different light intensities and wavelengths, the following equations for D* and noise equivalent power NEP are employed:³⁹

$$NEP = \frac{i_{n,rms}}{R} \tag{4}$$

and
$$D^* = \frac{\sqrt{AB}}{NEP} = \frac{R\sqrt{AB}}{i_{n,rms}}$$
 (5)

where A is the effective illuminated area of the channel = 4×10^{-7} cm⁻², B is the bandwidth, i_{n,rms} is the root mean square value of the noise current and R is the responsivity of the device. Since 1/f noise was shown to be the most dominant noise source in 2DLM transistors, ^{14,40} the noise level i_{n,rms} of the PdSe₂ FET was found by the Fourier transform (FFT) of the measured dark current (**Figure S5**) and was about ≈ 722 pAHz^{-1/2} per unit bandwidth (B = 1 Hz). The maximum D* and their corresponding NEP values of different wavelengths are plotted in **Figure 4b**. The FET shows the highest specific detectivity in the sensing range 420 nm to 1200 nm within the values of 1.63×10^8 to 1.72×10^{10} Jones. The D* values are similar to other reported 2DLM transistors. ⁴¹

According to the PdSe₂ transistors fabricated by mechanical exfoliation, they exhibited better photoresponse and responsivity in NIR region than the visible light spectrum.^{28,42} Although the polycrystalline structure of our PdSe₂ inevitably increases the free charge carriers from the defects and hence the conductivity, which result in a

relatively low on/off ratio. However, the transistor also shows a improved photoresponse in NIR region than the visible light region. Moreover, our PdSe2 transistor shows similar responsivity and detectivity values to them. The reported responsivity and detectivity of PdSe₂ transistor were about 708 A W⁻¹ and 8.2×10⁹ Jones at the wavelength of 1064 nm,⁴² while our responsivity and detectivity of PdSe₂ transistor is 1960 A W⁻¹ and 1.72×10^{10} Jones at the wavelength of 980 nm. It has been reported that some of the 2DLM photodetectors could achieve high responsivity which is attributed to long life time of the photocarriers, but not high mobility. Thus it will lead to a long response time in photodetection.¹⁴ However, as indicated by the aforementioned β values which are smaller than 1, the material defects in polycrystalline materials will act as the recombination center of the photocarriers and reduce the average life time. Regarding to this issue, although the thickness and synthesis are different, Table 1 shows our results with other large area MoSe₂, WSe₂, MoS₂, SnSe₂ and ReS₂ phototransistors with similar device architecture. 43-48 Our device exhibits a good balance between high responsivity and fast response time with the broadest detection range.

Table 1 Typical performance of the photodetectors with large area 2DLMs. (1L: 1 layer, FL: few layers, CVD: chemical vapor deposition)

Channel	Fabrication method	Response Time (ms)	<u>R (AW⁻¹)</u>	Detection range (nm)	Reference
9.2 nm PdSe ₂	Selenization	182 (rise), 1500 (fall)	1960	420 - 1200	This work
FL MoSe ₂	CVD	400	93.7	638	43
1L WSe ₂	CVD	1000	1.1	532	44
$1L \text{ MoS}_2$	CVD	1000	0.0011	488, 514.5	45
$1L \text{ MoS}_2$	CVD	220000	2200	532	46
FL SnSe ₂	CVD	100000	1.9	800	47
1L ReS ₂	CVD	100000	16.14	633	48

Conclusion

We successfully synthesized large area polycrystalline PdSe₂ by selenization of Pd films. The crystallinity, electrical and optoelectronic properties of PdSe₂ were shown to be suitable for photodetection. The responsivity of the PdSe₂ phototransistors can reach 1960 AW⁻¹ under the

980 nm illumination with relatively fast response time. Our work suggests that PdSe₂ is a promising material for broadband photodetection.

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Competing financial interests

The authors declare no competing financial interests.

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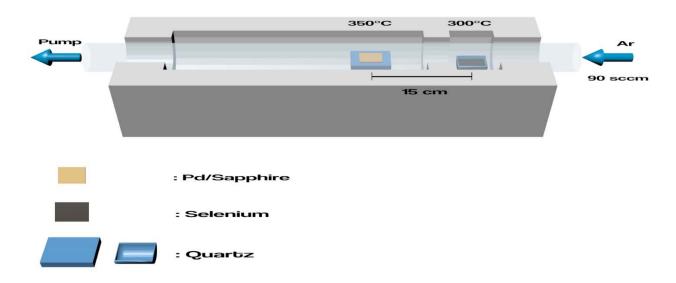
Supporting Information

Photoresponse of wafer-scale palladium diselenide films prepared by selenization method

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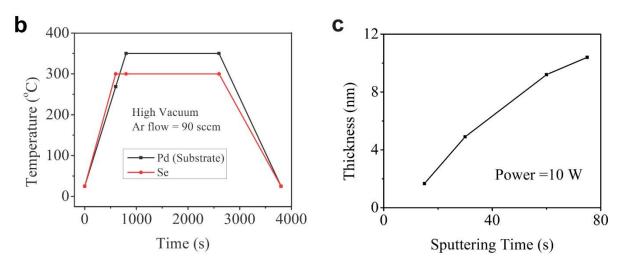


Figure S1 (a) Illustration of the selenization process. (b) Temperature profile of the selenization process. (c) The thickness of the PdSe₂ film as a function of Pd sputtering time.

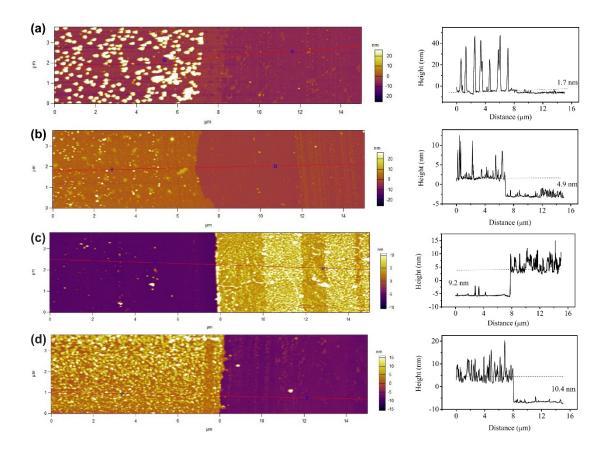


Figure S2 AFM measurement of the PdSe₂ films for different Pd deposition times: A) 15s, B) 30s, C) 60s and D) 75s.

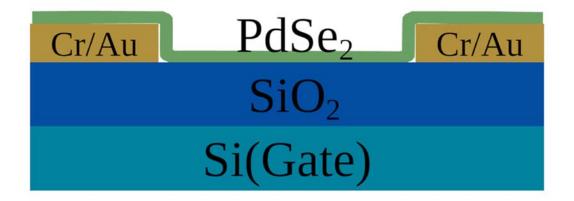


Figure S3 Schematic diagram of the PdSe₂ transistor.

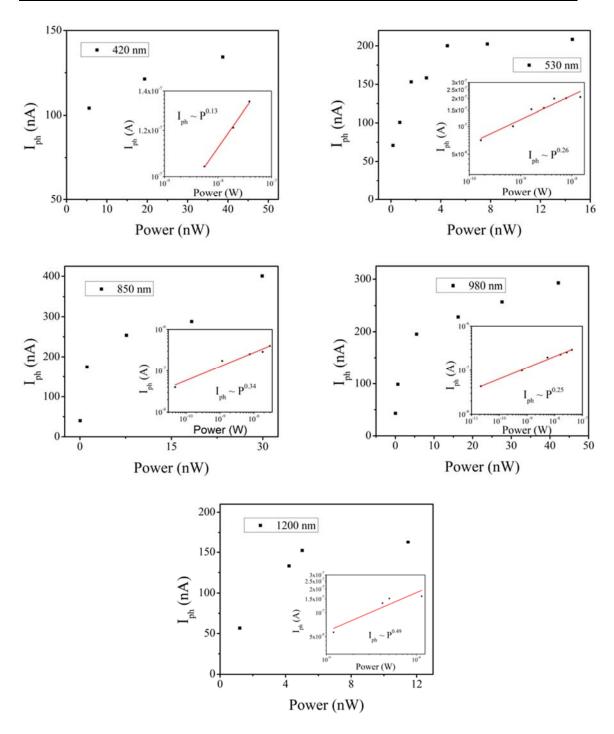


Figure S4 Photocurrent and power relationship in linear and logarithm scale. Linear relationship in logarithm scale are found in all sensing wavelength.

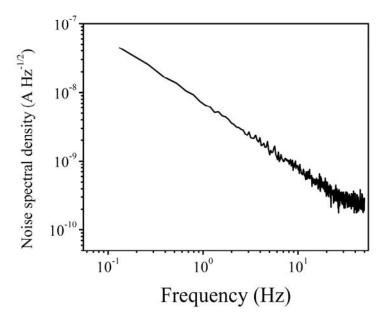


Figure S5 Analysis of noise spectral density of the device by the FFT of the dark current noise. The noise currents were measured at $V_{DS} = 3V$.

After the FFT analysis of the noise current, the 1/f noise spectral densities of the FET at the bandwidth B=1 Hz is ~ 722 pAHz^{-1/2}.